



SGC-S1700 SERIES

光学薄膜蒸镀设备

Vapor Deposition Equipment for Optical Thin Films

最适于树脂基板的镀膜！实现高水平的量产

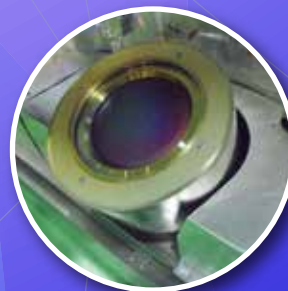
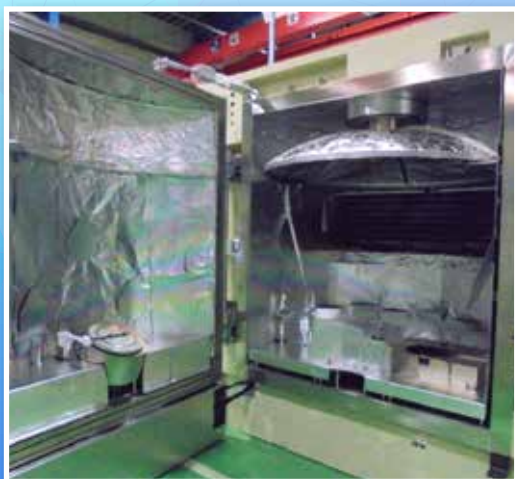
Ideal for film formation on resin substrates! Realizes mass production at high level

AR-coating-specific standard machine,
incorporating all the technologies of Sapio 1300
while assuring enhanced cost performance

沿袭Sapio1300的科技
拥有出色性价比
专门镀AR膜的标准机型



※Panel is optional



提供了诸如射频离子源，光学监控，
倒托盘等多种规格以供选择

Selectable from a variety of specifications such as; RF ion source,
Optical monitor and Inverting pallet

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【特长/选项等】

1. 采用高效排气系统，与 $\phi 1,300$ 蒸镀设备相比，镀膜处理时间仅增长10%左右
2. 每锅收纳基板数为 $\phi 1,300$ 蒸镀设备的2倍以上
3. 安装区域节省了空间，设计紧凑，整体高度降低

【Features/ Options】

1. Through the adoption of high efficiency exhaust system, compared with $\phi 1,300$ vapor deposition equipment, the coating treatment time only increases by about 10%.
2. The number of stored substrates per batch is twice or more of $\phi 1,300$ deposition equipment.
3. Space saving in the installation area, compact design with reduced overall height.

【用途/应用例】

树脂基板上形成防反射膜
光学镜

【Applications】

Anti-reflection film formation on resin substrate
Optical mirror

规格 Specifications

处理方法 Processing method	批次类型 Batch type
排气泵 Exhaust pump	26英寸DP x 2 + RP + MBP + 迈斯纳陷阱 26 inches DP x 2 + RP + MBP + Meissner trap
安装尺寸 Installation dimensions	W4,800mm x D7,600mm x H3,100mm W4,800mm x D7,600mm x H3,100mm
设备重量 Equipment weight	9,500kg 9,500kg
供电能力 Power supply capacity	AC200V (3 ϕ) / 约135kVA AC 200 V (3 ϕ) / about 135 kVA
真空槽尺寸 Vacuum tank size	$\phi 1,700$ mm $\phi 1,700$ mm

标配 Standard installation

水晶监控 COAT LEADER

Crystal monitor COAT LEADER



利用我们已经培养了多年的晶体器件制造设备的技术，并采用了利用网络分析仪来测量频率的方法，可以高精度地监测膜厚并控制速率。

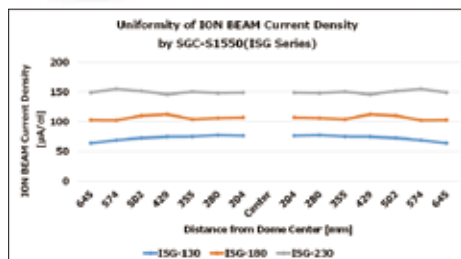
Taking advantage of the technology of quartz device manufacturing equipment that has been cultivated for many years by our company, the accuracy of this system has been significantly improved compared to the conventional measurement method by adopting the frequency measurement method with a network analyzer.

大功率射频离子源 ISG系列

High power RF ion source ISG series



它可在广范围内实现稳定放电，且可用于从光学滤光片的非移位膜到改进对树脂基材附着力的各种用途。



A wide range of stable discharges is possible, and it can be used in a variety of applications from non-shift films of optical filters to adhesion improvement to resin substrates.



株式会社 昭和真空
SHOWA SHINKU CO., LTD.

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検索

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根据日本外汇及对外贸易管理法的有关规定，该设备有可能归属为战略物资等出口限制产品。故如若将该设备运往日本以外的国家和地区，须向日本政府申办出口许可等必要相关手续。

This product may be applicable to export control products such as strategic raw materials which are regulated by the Foreign Exchange and Foreign Trade Control Law. Accordingly when you bring out the applicable products outside Japan, you should take a necessary action such as application of an export permit to the Government of Japan.

Web site 产品信息 Product Information

我们生产销售真空技术应用设备（真空设备），例如真空蒸镀设备和溅射设备等，主要是在真空中在特定基板上形成薄膜的设备。

SHOWA SHINKU manufactures and sells vacuum equipment such as Vacuum evaporation equipment, Sputtering equipment and etc., which uses vacuum technology and mainly forms thin films on a specific substrate.

https://www.showashinku.co.jp/product_c/index.html



如您正在考虑新的镀膜方案的话，务必和弊社进行商谈！

※本规格及设备外观，在设备改良有时会发生临时变更，恕不另行通知，恳请理解。

If you are looking for new film coating technology, Please ask our company!

* For the improvement of the product, please understand in advance that the specifications and external views are subject to change without prior notice.